

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10519699			
<b>Filing Date:</b>	14-Sep-2005			
<b>Title of Invention:</b>	Ion implantation device and a method of semiconductor manufacturing by the implantation of boron hydride cluster ions			
First Named Inventor/Applicant Name:	Thomas N. Horsky			
<b>Filer:</b>	John S. Paniaguas/Michael Tomsa			
<b>Attorney Docket Number:</b>	211843-00032			
Filed as Large Entity				
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>				
<b>Description</b>	<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
Submission- Information Disclosure Stmt	1806	1	180	180
<b>Total in USD (\$)</b>				<b>180</b>